

Notice of References Cited	Application/Control No. 10/758,807	Applicant(s)/Patent Under Reexamination CHU ET AL.	
	Examiner Biju Chandran	Art Unit 2835	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,144,286	11-2000	Moos et al.	338/22R
*	B	US-4,923,829	05-1990	Yasutomi et al.	501/95.3
*	C	US-2004/0238795 A1	12-2004	Duan et al.	252/500
*	D	US-2003/0067054 A1	04-2003	Chu et al.	257/551
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	W. Ruythooren et al., Electrodeposition for the synthesis of micrsystems, J. Micromech. Microeng. Vol 10, 2000, 101-107.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.